Theory of superfast fronts of impact ionization in semiconductor structures
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I. INTRODUCTION

Fronts of impact ionization can be excited in layered semiconductor structures such as $p^+\!-\!n\!-\!n^+$ diodes and $p^+\!-\!n\!-\!p\!-\!n^+$ dynistors.\(^1\!-\!5\) The front passage fills the structure with dense electron-hole plasma and hence leads to the transition of the reversely biased $p\!-\!n$ junction from low-conducting to high conducting state. Apart from microwave TRAPATT (TRAPPED Plasma Avalanche Triggered Transit) diodes,\(^6\!-\!12\) triggering of impact ionization fronts has been observed in high-voltage $p^+\!-\!n\!-\!n^+$ diodes manufactured from both Si (Refs. 3–6) and GaAs.\(^7\!-\!9\) In modern semiconductor electronics, excitation of ionization front is a unique nonoptical method capable of forming subnanosecond voltage ramps with kilovolt amplitudes. It has found numerous pulse power applications.\(^10\!,\!11\)

The mechanism of front propagation is based on avalanche multiplication of carriers by impact ionization and subsequent screening of the ionizing electric field due to the Maxwellian relaxation in the generated electron-hole plasma. The qualitative picture of the front passage is well-known (e.g., see Ref. 12 and references therein). In Fig. 1 we sketch the profiles of the electric field $E$ and the total carrier concentration $\sigma=\sigma_n+\sigma_p$ (here $n$ and $p$ are concentrations of electron and hole, respectively) in the $n$ base of reversely biased $p^+\!-\!n\!-\!n^+$ diode structure. The front propagates into a depleted region where the concentration of free carriers $\sigma_0$ is much smaller than the concentration of dopants $N_d$. In the depleted region the slope of electric field $qN_d/\varepsilon\varepsilon_0$ is controlled by the charge of ionized donors. The ionization zone travels into the depleted region with velocity $v_f$ that exceeds the saturated drift velocity $v_{ns}$ of electrons. This is possible due to a small concentration of free carriers $\sigma_0$ in the depleted region. The multiplication of these carriers starts as soon as the electric field becomes sufficiently strong; therefore, the ionization zone can propagate faster than the drift velocity. Generation of electron-hole pairs and subsequent separation of electron

![Fig. 1. Sketch of the electric field $E$ and total concentration of free carriers $\sigma=\sigma_n+\sigma_p$ (lower panel) in the $p^+\!-\!n\!-\!p^+$ structure during the passage of the ionization front. The field $E_f$ corresponds to the transition from linear low-field transport to saturated drift velocities. Coordinates $x$ and $z=x+v_f t$ correspond to stationary and comoving frames, respectively. Note relations $\sigma_0<<N_d, \sigma_m, \sigma_{pl}$ and between the initial concentration $\sigma_0$ in the depleted region, doping $N_d$ and plasma concentration $\sigma_{pl}$. The relation $\sigma^*>>\sigma_{pl}$ generally holds only for $v_{ns}>v_{pr}$ and can be broken for $v_{ns}<v_{pr}$.](https://example.com/fig1.png)
and hole in the electric field forms a screening region behind the ionization zone. Here the drift velocities remain saturated. The space charge in the screening region is due to excessive electron concentration. In the plasma layer the carrier concentration $\sigma_{pl}$ exceeds $N_d$ by several orders of magnitude; electric field is low and corresponds to linear ohmic regime. The described propagation of ionization front resembles the propagation of fingerlike streamers into preionized medium (see the discussion in Ref. 13).

The analytical theory of traveling ionization fronts in $p^+−n−n^+$ structures has been pioneered in Ref. 2 for TRAPATT diodes. This classical work is based on two crucial simplifications that make the theory essentially qualitative: (i) impact ionization coefficients are modeled by step functions; and (ii) electrons and holes are assumed to be identical. Later on the focus mostly shifted from analytical studies to numerical simulations.14–22 The demand for a quantitative analytical description remains strong, in particular, as ionization fronts in wideband materials17 and also operation at electric fields above the band-to-band Zener breakdown18,19 have a promising prospective. Analytical theory is also important to place ionization fronts in doped semiconductor structures into the general context of studies on front dynamics in spatially extended nonlinear systems.20–22 This article presents a theory of ionization front in a reversely biased $p^+−n−n^+$ structure. We take the asymmetry between electron and holes in both transport and impact ionization into account and assume a general form of impact ionization coefficients. The theory determines the maximum electric field in the traveling front $E_{tr}$, the voltage over the structure $u$, the concentration of the generated plasma $\sigma_{pl}$, and the electric field in plasma $E_{pl}$ as functions of front velocity $v_f$ and the $n$ base doping $N_d$ for self-similar propagation with constant velocity $v_f$. These results determine the instant front velocity $v_f$ as a function of the applied voltage $u$ and front position $x_f$ in cases when the front velocity and shape vary during the passage.

II. MODEL

A. Basic equations in drift-diffusion approximation

We investigate how an impact ionization front passes through a uniformly doped $n$ base of a reversely biased $p^+−n−n^+$ diode structure as sketched in Fig. 1. Heavily doped $p^+$ and $n^+$ layers play the role of contacts and are not taken into further consideration. The carrier dynamics in the $n$ base is described by the standard set of continuity equations and the Poisson equation,

\[
\begin{align*}
\partial_n - \partial_{[v_n(E)n]} - D_n \partial_n^2 &= G(n,p,E), \\
\partial_p + \partial_{[v_p(E)p]} - D_p \partial_p^2 &= G(n,p,E), \\
\partial_x E &= \frac{q}{\varepsilon_0}(p - n + N_d),
\end{align*}
\]

(1)

where $n,p$ and $v_n,v_p$ are electron and hole concentrations and drift velocities, respectively, $E$ is the electric field strength, $N_d$=constant is concentration of donors in the $n$ base, $q > 0$ is the elementary charge, $\varepsilon$ and $\varepsilon_0$ are the permittivity of the material and the absolute permittivity, respectively. We use the notation $v_{n,p}(E) > 0$ and take the actual direction of the carrier drift through the signs in Eqs. (1) into account. The impact ionization term is given by

\[
G(n,p,E) = \alpha_n(E)v_n(E)n + \alpha_p(E)v_p(E)p,
\]

(2)

where $\alpha_{n,p}(E)$ are impact ionization coefficients.

Let us introduce new variables,

\[
\sigma = n + p, \quad \rho = p - n.
\]

(3)

The first variable $\sigma$ is the total concentration of free carriers, the second one $\rho$ is proportional to the space charge of free carriers. Neglecting diffusion that does not play any role in the relevant scales (e.g., see Ref. 13), we present Eqs. (1) as

\[
\begin{align*}
\partial_t \sigma + \partial_x [v^+(E)\sigma + v^−(E)\rho] &= 2G, \\
\partial_t \rho + \partial_x [v^+(E)\sigma + v^−(E)\rho] &= 0, \\
\partial_x E &= \frac{q}{\varepsilon_0}[\rho + N_d],
\end{align*}
\]

(4–6)

where

\[
\begin{align*}
v^+(E) &= \frac{v_p(E) + v_n(E)}{2}, \\
v^−(E) &= \frac{v_p(E) - v_n(E)}{2}.
\end{align*}
\]

(7)

Note that for most semiconductors $v^−(E) < 0$.

Solving Eq. (6) for $\rho$, substituting this $\rho$ into the expression $\partial_x \rho$ in Eq. (5), and integrating over $x$, we obtain the conservation of the total current density in a one-dimensional system,

\[
J = q[v^+(E)\sigma + v^−(E)\rho] + \varepsilon \varepsilon_0 \partial_x E,
\]

\[
\partial_x J = 0.
\]

(8)

Here, the first and the second term correspond to the conduction and displacement components of the current density $J$, respectively. In the following we replace Eq. (5) by Eq. (8).

B. Self-similar propagation of the ionization front

We consider the fronts moving in the same direction as electrons drift—so-called negative fronts. We choose $E > 0$; hence, electrons and negative fronts move to the left (cf. Fig. 1). Positive fronts in $n^+−p−p^+$ structures that move in the same direction as hole drift can be described by exchanging electrons and holes in Eqs. (1) and replacing the donor concentration $N_d$ by the same acceptor concentration $N_a$. For the self-similar front motion with velocity $v_f=$constant, we get

\[
\begin{align*}
\sigma(x,t) &= \sigma(x + v_f t), \\
\rho(x,t) &= \rho(x + v_f t), \\
E(x,t) &= E(x + v_f t),
\end{align*}
\]

where we fixed the notation such that the fronts move with a positive velocity $v_f > 0$ in the negative $x$ direction. Then, in the comoving frame $z = x + v_f t$, Eqs. (4), (8), and (6) become

\[
\begin{align*}
df_2 &= [v_f + v^+ - v^+\rho] = 2G,
\end{align*}
\]

(9)
Typically the electric field at the left boundary is zero. Since the front propagates with velocity \( v_f \) we will see in the next section, a constant velocity \( v_f \) implies a time-independent total current density \( J = \text{constant} \).

### C. Relation between the current density and the front velocity

Using Eq. (11) to eliminate \( d_E \) from Eq. (10), we find

\[
\begin{align*}
J &= q\nu_j N_d + qj, \\
J &= v_f \alpha_0 + [v_f + v^-]j, \\
\alpha_0 &= n_0 + p_0, \quad p_0 = p_0 - n_0, \quad v^+ = \frac{v_{ns} + v_{ps}}{2}, \quad v^- = \frac{v_{ps} - v_{ns}}{2}.
\end{align*}
\]

Since \( \alpha_0, p_0 \ll N_d \) and the second term in Eq. (12) is negligible. Hence \( J = qN_d \nu_f \). This result is well known and physically clear: since the front propagates with velocity \( v_f \) into a charged medium with space-charge density \( qN_d \), the current density \( qN_d \nu_f \) is required to neutralize the space charge of the ionized donors. Hence for a planar front, self-similar propagation with constant velocity \( v_f \) corresponds to a fixed total current in the external circuit \( dJ = 0 \).

Although the initial carrier density in the depleted region is low, \( \alpha_0 \ll N_p \), its presence is required for the front to propagate with a velocity \( v_f \) that exceeds the electron drift velocity \( v_{ns} \). This fast propagation mode is possible because these initial carriers multiply in an avalanche-like manner as soon as the electric field exceeds the ionization threshold.

In the case under study the concentrations \( n_0 \) and \( p_0 \) are not permanently nonvanishing in the medium the front propagates into. On the contrary, a certain mechanism creates these carriers in the \( n \) base just before the front starts to travel, and it actually triggers this propagation. This mechanism is not universal and depends on the specific design and operation mode of a semiconductor device. In microwave TRAPPAT diodes the carriers that remain in the structure from the previous front passage serve as initial carriers for the next passage.\(^{12} \) In contrast, in high-voltage diodes used as pulse sharpeners the time period between subsequent front passages is so long (typically \( > 100 \mu s \)) that each front passage represents an independent event.\(^{3-5} \) Between the pulses the reverse voltage is kept close to the stationary breakdown voltage \( u_b \). During this waiting period, which can be arbitrarily long, the leakage current is much smaller than \( qj \), so that \( n \) base is essentially empty. To trigger the front the applied voltage \( u \) is being rapidly increased above \( u_b \). Experiments show that the front starts to travel when \( u \) exceeds \( u_b \) several times.\(^{3-5} \) It appears that in these devices the initial carriers are generated by field-enhanced ionization of deep-level electron traps.\(^{23-25} \) The release of electrons bound on these deep centers triggers the front and provides conditions for its superfast propagation.\(^{26} \) Here, we focus exclusively on the stage when the ionization front is already traveling and refer to Refs. 24 and 25 for the detailed discussion on triggering and initial carriers problems. We assume that concentration of initial carriers suffices for using our density model and we treat \( \alpha_0 \) as an input parameter of our model.

### D. Final set of equations

Equation (12) allows us to express the “space charge” \( \rho \) via the total concentration \( \sigma \) as

\[
\rho = -\frac{v_f}{v_f + v^-} \frac{j}{(E)} + \frac{j}{v_f + v^-} \sigma + \frac{j}{v_f + v^-} j = 2G.
\]

The impact ionization can be expressed via variables \( \sigma \) and \( \rho \) as

\[
G(\sigma, \rho, E) = \beta^\prime(E) \sigma + \beta^\prime(E) \rho.
\]

with impact ionization frequencies

\[
\beta^\prime = v_{ns}(E) \alpha_0(E) + v_{ps}(E) \alpha_0(E).
\]

Using Eq. (14) again to exclude \( \rho \), we obtain

\[
G(\sigma, E) = G(\sigma, \rho, E) + \frac{\beta^\prime}{v_f + v^-} j
\]

Finally, we express \( \rho \) by \( \sigma \) in the Poisson equation, Eq. (11). This leads to Eq. (20) below.

The two equations for the total carrier concentration \( \sigma \) and the field \( E \),

\[
d_J \left[ \frac{(v_f + v^-)^2 - (v^+)^2}{v_f + v^-} \sigma + \frac{(v_f + v^-)^2}{v_f + v^-} j \right] = 2G(\sigma, E, v_j) \sigma + \frac{\beta^\prime}{v_f + v^-} j.
\]
\[ d_x E = b - \frac{q}{\varepsilon_e v_f + v^-} \varepsilon_o \sigma, \]
\[ b = \frac{q}{\varepsilon_e} \left( N_d + \frac{j}{v_f + v^-} \right), \quad (20) \]

with the known functions \( v^- (E), \beta^N (E), \) and \( \beta_{\text{eff}} (E, v_f) \) and the constant
\[ j = v^+ \sigma + [v_f + v^-] \rho, \quad (21) \]

completely describe the self-similar propagation of impact ionization front.

Summarizing, we have first substituted the variables \((n, p, E)\) by the new variables \((\sigma, \rho, E)\), and then we have expressed \( \rho \) by the conserved total current \( J \) or \( j \) and \( \sigma \). In this way we have eliminated the third equation from the original set Eq. (1) using the fact that the local space-charge density \( \rho \) is no independent variable when the conserved total current \( J \) and the local carrier density \( \sigma \) and field \( E \) are fixed. The form of the final equations, Eqs. (19) and (20), is one of two ordinary differential equations of first order.

E. Special and limiting cases

Apart from the general case \( v_n (E) \neq v_p (E), \) \( \alpha_n (E) \neq \alpha_p (E) \), it is instructive to consider the following special cases:

\( a) \) \( v_n (E) = v_p (E) = v(E), \) \( \alpha_n (E) = \alpha_p (E) = \alpha(E), \)
\( b) \) \( v_n (E) = v_p (E) = v(E), \) \( \alpha_n (E) = \alpha(E), \) \( \alpha_n (E) = 0, \)
\( c) \) \( v_n (E) = v_p (E) = v(E), \) \( \alpha_n (E) = \alpha(E), \) \( \alpha_p (E) = \alpha(E). \)

In case (a) electrons and holes are fully equal, in cases (b) and (c) their drift velocities are equal, but impact ionization takes place due to only one type of carriers. For example, cases (b) and (c) are simplified but reasonable approximations for Si and SiC,\(^{27}\) respectively.

Another two limiting cases provide insight into the front dynamics for materials where the asymmetry between positive and negative carriers is very strong,

\( d) \) \( v_n (E) = v(E), \) \( v_p (E) = 0, \) \( \alpha_n (E) = \alpha(E), \) \( \alpha_p = 0, \)
\( e) \) \( v_p (E) = v(E), \) \( v_n (E) = 0, \) \( \alpha_n (E) = \alpha(E), \) \( \alpha_n = 0. \)

Below we refer to these special cases as cases (a), (b), (c), (d), and (e); we also use these labels to denote the respective curves in the figures.

III. GENERAL PROPERTIES OF THE STATIONARY FRONT PROPAGATION

The main parameters of the traveling front are the maximum electric field \( E_m \), the width \( \ell_p \) of the screening region, the voltage \( u \) across the \( n \) base, the carrier concentration \( \sigma_{\rho 0} \), and electric field \( E_p \) in the electron-hole plasma behind the front (Fig. 1). [In Fig. 2 we sketch the respective \( \sigma (E) \) dependence that follows from \( E(x) \) and \( \sigma(x) \) dependences shown in Fig. 1.] In this section we relate these parameters to the front velocity \( v_f \), the doping level \( N_d \), and the initial concentration \( \sigma_0 \) in the deleted region, assuming that \( v_f = \) constant and front propagation is self-similar. Note that according to Eq. (12), the velocity \( v_f \) can be expressed by the current density \( J = q N_d v_f \).

A. Ordering of scales

In semiconductors the drift velocities \( v_{n,p} (E) \) typically saturate in electric fields above the characteristic fields \( E_{ns,ps} \) that are much smaller than the effective threshold of impact ionization. Consequently, in the range of electric fields where impact ionization sets in \( (\alpha_n, p \neq 0) \) the velocities of free carriers do not depend on electric field \( [v^+ (E) = v^+ p, v^- (E) = v^- p] \) in Eqs. (19)–(21)]. On the other hand, the generation term is negligible in the range of electric fields where the nonlinearity of \( v_{n,p} (E) \) dependencies is essential.

For semiconductors where the drift velocities \( v_{n,p} (E) \) depend monotonically on the field, the approximations

\[ v_n (E) = v_n \frac{E}{E + E_{ns}}, \quad v_p (E) = v_p \frac{E}{E + E_{ps}}, \quad (22) \]

and their modifications are widely used.\(^{28}\) The impact ionization coefficients for electrons and holes are usually modeled as

\[ \alpha_n (E) = \alpha_{n 0} \exp (E_{th}/E), \quad \alpha_p (E) = \alpha_{p 0} \exp (E_{th}/E). \quad (23) \]

This approximation is known as the Townsend approximation in gas discharge physics.\(^{30}\) The characteristic transport fields \( E_{ns,ps} \) are typically much smaller than the impact ionization fields \( E_{n, p 0}; E_{n, p 0} \ll E_{n, p 0}. \) For example, in Si we have \( E_{ns,ps} \approx 10^4 \text{ V/cm}, \) whereas \( E_{n, p 0} \approx 10^6 \text{ V/cm}. \)\(^{27}\) It should be noted that none of these explicit approximations Eq. (22) or Eq. (23) is needed for our analytical results.

Equations (19)–(21) will be solved separately in the range of strong electric fields \( E_s < E \leq E_0 \) where impact ionization takes place and the range of moderate-to-low electric field \( E \leq E_s \) where transition from high-field transport to low-field transport occurs and the plasma layer is formed. Due to the overlap between these two regions the obtained solutions can be sewn together, providing a consistent description.
B. Equations in the high-field region

For $E > E_{\text{as,pr}}$, we assume that carriers drift with constant velocities $v_{n,p}(E) = v_{n,p}$. Then, Eqs. (19)–(21) become

$$d_z \sigma = \lambda \beta_{\text{eff}}(E, v) \sigma,$$

$$d_E = b - c \sigma,$$

$$j = v_f \sigma + (v_f - v_i) p,$$

where

$$\lambda = \frac{2 (v_f + v_i)}{(v_f + v_i)^2 - (v_i^2)},$$

$$b = \frac{q}{\varepsilon \varepsilon_0} \left( N_d + \frac{j}{v_f + v_i} \right) \approx \frac{q N_d}{\varepsilon \varepsilon_0},$$

$$c = \frac{q}{\varepsilon \varepsilon_0 (v_f + v_i)},$$

$$v_i = \frac{v_{ns} \pm v_m}{2}.$$

The coefficients $\lambda$, $b$, and $c$ are constants. When deriving Eq. (24) from Eq. (19), we neglect the second term on the right-hand side. This is justified because the order of magnitude value of this term is $\beta (v^f / v) \sigma_0$, which is much smaller than the first term. We also take into account that $j (v_f + v_i) - (v_f / v) \sigma_0 \ll N_d$ in the expression for $b$.

C. Carrier concentration just behind the ionization zone

At the point $x_f$ where electric field reaches the maximum value $E_m$, the slope of electric field profile is equal to zero (see Fig. 1). In the comoving frame $x_f$ corresponds to the point $z_m = x_f + v_d t$ that does not vary in time. It follows from $d_z E = 0$ and Eq. (25) that

$$\sigma_m - \sigma(z_m) = \frac{b}{c} = \frac{v_f + v_i}{v_f + v_i} N_d + \frac{j}{v_f + v_i} = \frac{v_f + v_i}{v_f + v_i} N_d.$$

Dividing Eq. (24) by Eq. (25) we exclude $z$, and then employ Eq. (28). This yields

$$\sigma_m - \sigma = \frac{\lambda}{c} \beta_{\text{eff}}(E, v_f) dE.$$

Let us denote as $\sigma^*$ the concentration $\sigma$ which is reached just behind the ionization zone (Fig. 1). Then, the integrals of the left-hand side of Eq. (29) from $\sigma_0$ to $\sigma_m$ and from $\sigma^*$ to $\sigma_m$ are both equal to the integral of the right-hand side from 0 to $E_m$ (see Fig. 2).

$$\int_{\sigma_0}^{\sigma_m} \frac{\sigma_m - \sigma}{\sigma} d\sigma = \int_{\sigma^*}^{\sigma_m} \frac{\sigma_m - \sigma}{\sigma} d\sigma = \frac{\lambda}{c} \int_0^{E_m} \beta_{\text{eff}}(E, v_f) dE.$$

Taking integrals over $\sigma$, we find the relation between the concentration behind the front $\sigma^*$, front velocity $v_f / v_i$, the doping level $N_d$, and initial concentration $\sigma_0$.

FIG. 3. Concentration $\sigma^*$ just behind the ionization zone as a function of $v_f / v_i^*$ for different values of $\sigma_0 / N_d$. Thick solid lines 1, 2, 3 correspond to symmetric case $v_i^* = 0$. Dotted lines 1d, 2d, 3d and dashed lines 1e, 2e, 3e correspond to the two limiting asymmetric cases $v_i^* / v_f^* = -1$ [immobile holes, case (d)] and $v_i^* / v_f^* = 1$ [immobile electrons, case (e)], respectively. Curves of first, second, and third series correspond to $\sigma_0 / N_d = 10^{-7}$, $10^{-4}$, and $10^{-5}$, respectively. Thin solid line 4 shows concentration $\sigma_m$ at the point of maximum electric field for the symmetric case $v_i^* = 0$.

$$\sigma^* = \sigma_m \ln \frac{\sigma^*}{\sigma_0} + \sigma_0 \approx \sigma_m \ln \frac{\sigma^*}{\sigma_0}.$$

The concentration $\sigma^*$ does not depend on $\beta_{\text{eff}}$ and thus not on the specific form of $\sigma_0 / N_d$. Equation (28) generalizes Eq. (29) in Ref. 2.

In Fig. 3 we show $\sigma^*$ and $\sigma_m$ as functions of $v_f / v_i^*$ for different values of $\sigma_0 / N_d$. Solid lines 1, 2, 3 correspond to the symmetric case $v_i^* = 0$. These dependencies are valid for all three special cases (a), (b), and (c) (see Sec. II E) if $v_i^*$ is replaced by $v_i$. We see that $\sigma^*$ is approximately 10 times larger than $\sigma_m$ (line 4), whereas $\sigma_m$ exceeds $\sigma_0$ by several orders of magnitude. Dashed lines 1d, 2d, 3d and dotted lines 1e, 2e, 3e show $\sigma^*$ for two extreme asymmetric cases $v_i^* / v_f^* = \mp 1$ that correspond to immobile holes [case (d), $v_{ns} = 0$] and immobile electrons [case (e), $v_{ns} = 0$], respectively. In the case (d) of immobile holes $\sigma^* - 0$ when $v_f / v_i^* < 1$ (although the part $v_f < 2 v_i^* = v_{ns}$ is unphysical). In contrast, in the case (e) of immobile electrons $\sigma^*$ practically does not depend on $v_f$ for $v_f / v_i^* < 1$. This plateau exists for $v_f > 0$ and corresponds to the interval of front velocities $v_{ns} < v_f < v_{ps}$ (recall that for negative front $v_f \gtrless v_{ns}$). Even for the limiting cases $v_f / v_i^* = \mp 1$ the effect of transport asymmetry is small for $v_f / v_i^* > 10$. Actual values of $v_i^* / v_f^*$ are much smaller: at room temperatures we have $v_i^* / v_f^* \approx -0.1, -0.05, \text{and} -0.3$ for Si, GaAs, and SiC, respectively.27

According to Eq. (26) the space charge of free carriers behind the ionization zone is proportional to $\sigma^*$.

$$\rho^* = - \frac{v_i^*}{v_f + v_i^*} \sigma^* + \frac{j}{v_f + v_i^*} = - \frac{v_i^*}{v_f + v_i^*} \sigma^*.$$

Electron and holes concentrations $n^*, p^* = (\sigma^* \div \rho^*) / 2$ are recovered as

$$n^* = \frac{v_f + v_{ps}}{2 v_f + v_{ps} - v_{ns}} \sigma^*.$$
\[ p^* = \frac{v_f - v_{ns}}{2v_f + v_{ps} - v_{ns}} \sigma^*. \] (33)

The appearance of negative space charge \( p^* = p^* - n^* < 0 \) is a combined effect of spatially inhomogeneous ionization and separation of electrons and holes in strong electric field.

D. Maximum electric field

The maximum field \( E_m \) is determined by integrating Eq. (29),

\[ \int_0^{E_m} \beta_{cl}(E) dE = \frac{b}{\lambda} \left( \frac{\sigma_m}{\sigma_0} - 1 + \frac{\sigma_0}{\sigma_m} \right). \] (34)

Substituting the expressions for \( \beta_{cl}(E) \), \( \lambda \), and \( \sigma_m \), we obtain the explicit formula

\[ \frac{v_s^* - v_s}{v_f + v_s} \int_0^{E_m} \alpha_s(E) dE + \frac{v_s^* + v_s}{v_f + v_s} \int_0^{E_m} \alpha_p(E) dE = \frac{qN_d}{\varepsilon \varepsilon_0} \left( \frac{v_f + v_s N_d}{v_s \sigma_0} \right) - 1. \] (35)

Straightforward numerical integration of Eq. (35) for given dependencies \( \alpha_{s,p}(E) \) makes it possible to determine \( E_m \) as a function of \( v_f \), and \( \sigma_0/N_d \) for any semiconductor material.

For the special cases (a), (b), (c), (d), and (e) (see Sec. II E) and the Townsend’s dependence \( \alpha(E) = \alpha_0 \exp(-E_0/E) \), Eq. (35) yields

\[ \int_0^{E_0} \exp(-1/y) dy = \frac{E^*(v_f/v_s, \sigma_0/N_d, \alpha_0)}{E_0}, \] (36)

\[ E^* = \frac{b}{\alpha_0} \frac{v_s^2 - v_s^2}{2v_f v_s} \left[ \ln \left( \frac{v_f N_d}{v_s \sigma_0} \right) - 1 \right] \] for case (a), (37)

\[ E^* = \frac{b}{\alpha_0} \frac{v_f v_s}{v_s} \left[ \ln \left( \frac{v_f N_d}{v_s \sigma_0} \right) - 1 \right] \] for cases (b) and (c), (38)

\[ E^* = \frac{b}{\alpha_0} \frac{v_f v_s}{v_s} \left[ \ln \left( \frac{2v_f + v_s N_d}{v_s \sigma_0} \right) - 1 \right] \] for cases (d) and (e). (39)

The dimensional coefficient \( b/\alpha_0 \) in \( E^* \) has a meaning of change of the electric field on the length of impact ionization \( \alpha_0^{-1} \) for the slope \( d.E/b \) which is determined by the doping level \( N_d \). For realistic parameters \( b/\alpha_0 \ll E_0 \). Comparing Eq. (38) with Eq. (39), we see that asymmetry of transport properties has a logarithmically weak effect on \( E_m \).

We solve Eq. (36) numerically and show \( E_m/E^* \) as a function of \( E_0/E^* \) in Fig. 4. Together with Eqs. (37)–(39), this dependence makes it possible to determine \( E_m \) for given values of \( v_f/v_s, \sigma_0/N_d, \alpha_0 \), and \( E_0 \) for the special cases (a)–(e). [Note that \( E_m/E^* \rightarrow 1 \) when \( E_0/E^* \rightarrow 0 \). This limit corresponds to ultrastrong electric field when \( \alpha(E) \rightarrow \alpha_0 \).] \( E_m \) increases with \( E_0 \) because the effective threshold of impact ionization becomes higher.

In Fig. 5 we show \( E_m \) as a function of \( v_f/v_s \) for different values of \( \sigma_0/N_d \). Thick solid lines 1a, 2a, 3a correspond to the symmetric case (a) [Eq. (37)], thin solid lines 1b, 2b, 3b and dashed lines 1c, 2c, 3c correspond to the cases of “monopolar ionization” (b) and (c) [Eq. (38)], respectively. \( E_m \) is the smallest for the symmetric case \( \alpha_s = \alpha_p \) because both types of carriers are involved in impact ionization. Curves 1c, 2c, 3c are “discontinuous;” \( E_m \) tends to a finite value when \( v_f/v_s \rightarrow 1 \), whereas we expect \( E_m \rightarrow 0 \) for \( v_f/v_s = 1 \) as it is for the curves 1a, 2a, 3a and 1b, 2b, 3b. This feature results from the assumption \( \alpha_s = 0 \) and disappears for arbitrary small but nonzero value of \( \alpha_p \). Physically it means that impact ionization by electrons that move parallel to the front is important at low front velocities \( v_f\sim v_s \) even in the case \( \alpha_s \ll \alpha_p \). The curves for two types of monopolar ionization (b) and (c) become close with increase of \( v_f \). The dependencies \( E(v_f) \) calculated for fully immobile holes or electrons [cases (d) and (e)], Eq. (39), the respective curves not shown] turn out to be very close to the cases of monopolar ionization (b) and (c) [Eq. (38)], curves 1b, 2b, 3b and 1c, 2c, 3c, respectively]; the difference is smaller than 2% in the whole interval \( 1 < v_f/v_s < 100 \). It means that \( E_m \) is much more influenced by the asymmetry of impact ionization coefficients than by the asymmetry of drift velocities. We also see that \( E_m \) and hence the effective width of ionization zone \( \ell_f \) decrease with \( \sigma_0 \). This observation explains why the concentration \( \sigma^* \) (see Fig. 3) also decreases with \( \sigma_0 \). In Fig. 5 we choose \( b/(\alpha_0E_0) = 0.0002 \). For Si this value corresponds to \( N_d = 10^{14} \) cm\(^{-2} \), which is a typical doping level for high-voltage Si structures.\(^{3,5} \) Since in Si impact ionization by electrons dominates and \( v_{ns} = v_{ps} \) (Ref. 27), curves 1b, 2b, and 3b provide a good approximation for this material.

Figure 6 shows the dependence \( E_m(v_f) \) for different values of \( b/(\alpha_0E_0) \) and the fixed value of \( \sigma_0/N_d \). \( E_m \) increases with \( N_d \) due to the decrease of the effective width of ionization zone \( \ell_f \) and decreases with \( \sigma_0 \) due to the more efficient impact ionization.

The \( E_m(v_f) \) dependencies obtained for the case of symmetric ionization \( \alpha_s = \alpha_p \) and ionization by electrons (curves 1a, 2a, 3a and 1b, 2b, 3b in Figs. 5 and 6) can be fitted by the square-root function.
FIG. 5. Maximum electric field $E_m$ as a function of $v_i/v_s$, for different values of $\sigma_0/N_d$ according to Eq. (36). Thick solid curves 1a, 2a, 3a correspond to the symmetric case $\alpha_s(E) = \alpha(E)$, $v_m = v_p$, [case (a), Eq. (37)]. Thin solid curves 1b, 2b, 3b correspond to impact ionization by electrons $\alpha_s(E) = 0$, $v_m = v_p$, [case (b), Eq. (38)]. Dashed curves 1c, 2c, 3c correspond to impact ionization by holes $\alpha_s(E) = 0$, $v_m = v_p$, [case (c), Eq. (38)]. Curves of first, second, and third series correspond to $\sigma_0/N_d = 10^{-4}$, $10^{-4}$, and $10^{-5}$, respectively. The parameter $b/(\alpha_0 E_0)$=0.0002 corresponds to the doping level $N_d = 10^{14}$ cm$^{-3}$ in Si.

$E_m(v_i) - E_{th} \sim E_0 v_i v_s - 1$, \hspace{1cm} (40)

where $E_{th} = 0.15, \ldots, 0.2E_0$ plays the role of the effective threshold of impact ionization. This fit is quantitatively accurate for $v_i/v_s > 2$ and remains qualitatively correct for $1 < v_i/v_s < 2$. Straightforward examination of Eq. (35) shows that the square-root dependence corresponds to the piecewise linear approximation of the impact ionization coefficient $\alpha(E)$,

$\alpha(E) \sim \Theta(E - E_{th})/E_{th}$, \hspace{1cm} (41)

where $\Theta(E)$ is the step function. The function Eq. (41) approximates the Townsend’s dependence $\alpha(E) = E_0 \exp(-E_0/E)$ reasonably well in the most important interval of electric fields $0.3, \ldots, 0.7E_0$ (see the inset to Fig. 6).

[Previously the approximation Eq. (41) has been discussed in the theory of finger-like streamers in Ref. 30.] It is remarkable that the dynamics of ionization fronts reveals the existence of effective threshold electric field $E_0 \approx 0.2E_0$ in spite of the absence of any kind of cutoff at low electric fields in the Townsend’s dependence itself. In particular, the square-root dependence Eq. (40) implies that $\ell_i \sim \ell_i^2$ if we define $\ell_i \approx (E_m - E_{th})/b$.

E. Width of the screening region

The screening region is situated just behind the ionization zone (Fig. 1). Here, the electric field is insufficient for impact ionization, but the drift velocities remain saturated. According to Eqs. (19) and (21) in this interval of electric fields the concentration $\sigma$ and space charge $\rho$ are conserved and maintain values $\sigma^*$ and $\rho^*$ determined by Eqs. (31) and (32). The slope of electric field in this region is determined as

$$dE/dv_i = q/(\rho^* + N_d).$$

Taking into account Eqs. (28) and (31), we find the ratio between the slope $dE/dv_i$ in the screening region and the slope $b$ in the depleted region,

$$|dE/b| \approx \frac{v_i^+}{v_i^+ + v_s^+} \alpha^* = \frac{\ln \sigma^*/\sigma_0 - 1}{\sigma_0 - 1}. \hspace{1cm} (42)$$

The width $\ell_\rho$ of the screening region can be evaluated as

$$\ell_\rho \approx \frac{E_m}{|dE/b|} = \frac{E_m}{b[\ln(\sigma^*/\sigma_0) - 1]}. \hspace{1cm} (43)$$

Calculating $\ell_\rho$ in this way, we include in it a part of the ionization zone (see Fig. 1) and hence somewhat overestimate the actual width of the screening region. On the other hand, Eq. (43) gives an idea of the effective front width since it accounts for the two regions of most dramatic change in concentration and electric field: the region of most rapid increase of concentration from $E_m$ to the final value $\sigma^*$ (by approximately one order of magnitude) and the region of steep drop of electric field from $E_m$ to $E_{th} \ll E_m$.

We show $|dE/b|$ as a function of $v_i/v_s^+$ in Fig. 7. Solid lines correspond to the symmetric case $v_s^+=0$ for different values of $\sigma_0$. These curves correspond also to the special cases (a), (b), and (c) if $v_s^+$ is replaced by $v_s$. The electric field profile in the screening region is approximately 10–20 times steeper than in the depleted region. The slope $|dE/b|$ has a weak logarithmic dependence on $v_i$ and decreases with $\sigma_0/N_d$. Dashed lines and dotted lines represent $|dE/b|$ for two limiting asymmetric cases $v_s^+ \neq 0$ [case (d), immobile holes] and $v_i^+ > v_s^+$ [case (e), immobile electrons]. Similar to $\sigma^*$, $|dE/b|$ has a weak dependence on the asymmetry of saturated drift velocities ($v_i^+ \neq 0$) for sufficiently large $v_i$.
FIG. 7. Slope of electric field in the screening region $|dE|/b$ normalized by the slope in the depleted region $b=qN_d/eE_0$ as a function of $v_j/v^*_s$ for different values of $\alpha_0/N_d$. Solid lines 1, 2, 3 correspond to the symmetric case $v^*_s=0$. Dotted lines 1d, 2d, 3d and dashed lines 1e, 2e, 3e correspond to the two limiting asymmetric cases $v^*_s/v^*_f=1$ [immobile holes, case (d)] and $v^*_s/v^*_f=1$ [immobile electrons, case (e)], respectively. Curves of first, second, and third series correspond to $\alpha_0/N_d=10^{-4}$, 10$^{-3}$, and 10$^{-2}$, respectively.

**F. Transition from high-field to low-field region**

In the region where electric field is insufficient for impact ionization, it follows from Eq. (19) that

$$\frac{[v_f + v^*(E)]^2 - [v^*(E)]^2}{v_f + v^*(E)} \sigma - \frac{v^*(E)}{v_f + v^*(E)} = j = \text{const},$$

where the second small term is negligible. Employing conservation of this quantity, we find explicit expressions for $\sigma$ and $\rho$.

$$\sigma(E) = \frac{\left(v_f^2 + v^*_f\right)^2 - [v^*(E)]^2}{v_f^2 + v^*_f} \sigma^*,$$

$$\rho(E) = \frac{v^*(E)}{v_f} \frac{\left(v_f^2 + v^*_f\right)^2 - [v^*(E)]^2}{v_f^2 + v^*_f} \sigma^*.$$  

For the special cases (a), (b), and (c), this yields

$$\sigma(E) = \frac{v_f^2 - v^*_f}{v_f} \sigma^*,$$

$$\rho(E) = -\frac{v(E)}{v_f^2} \frac{v_f^2 - v^*_f}{v_f^2 - v^*_f} \sigma^*.$$  

If $v(E)$ is monotonic, then according to Eq. (46) $|\rho(E)|$ monotonically decreases with decrease of $E$. The transition to neutral plasma occurs when $|\rho(E)|$ reaches $N_d$ and $E$ reaches a certain constant asymptotic value. In semiconductors with nonmonotonic $v(E)$ dependence (e.g., GaAs) with maximum at $E < E^*$, we expect that $|\rho(E)| > |\rho^*|$ near $E$, but the transition to plasma at lower electric fields occurs in the same way as for monotonic $v(E)$.

**G. Parameters of the plasma region**

Plasma concentration and electric field in plasma are denoted as $\sigma_{pl}$ and $E_{pl}$, respectively (Fig. 1). Generally, these parameters are determined by Eqs. (21) and (44) together with the neutrality condition $\rho_{pl} = -N_d$.

For the general asymmetric case $v^*(E) \neq 0$ we approximate the drift velocities in plasma by the Ohm law $v_{pl}(E) = \mu_{ef} E$, $v_{pl} = \mu_{ef} E$ [note that for the approximations Eq. (22) $\mu_{pl,ef} = E_{pl,ef}/E_{na,pl}$]. This yields

$$\frac{(v_f + v^*_f)^2 - (v^*_f)^2}{v_f + v^*_f} \sigma^* = \frac{(v_f + \mu_{pl} E_{pl})^2 - (\mu_{pl} E_{pl})^2}{v_f + \mu_{pl} E_{pl}} \sigma_{pl},$$

$$j = \mu_{pl} \sigma_{pl} E_{pl} + (v_f + \mu_{pl} E_{pl})(-N_d),$$

$$\mu_{pl} = \frac{\mu_n \pm \mu_p}{2}. \tag{48}$$

Expressing $E_{pl}$ via $\sigma_{pl}$ in Eq. (48), neglecting $j$, and substituting in Eq. (47), we find explicit formulas for $\sigma_{pl}$.

$$\sigma_{pl} = \frac{1}{2} A \sigma^* \left[ 1 + \sqrt{1 + \frac{4 N_d}{A \sigma^*} \left( \frac{N_d}{A \sigma^*} - \frac{\mu_n}{\mu_p} \right)} \right], \tag{49}$$

$$E_{pl} = E_{pl}^* \frac{v_f v^*_f}{\sigma_{pl} N_d - \mu_n/D_p^*/}, \tag{50}$$

Expansion over $N_d/A \sigma^*$ leads to

$$\sigma_{pl} = A \sigma^* + \frac{N_d}{A \sigma^*} - \frac{\mu_n}{\mu_p} N_d = A \sigma^* = \frac{(v_f + v^*_f)^2 - (v^*_f)^2}{v_f (v_f + v^*_f)} \sigma^*.$$  

$$E_{pl}^* = \frac{v_f v^*_f}{\sigma_{pl} N_d - \mu_n/D_p^*/}. \tag{51}$$

Electron and hole concentrations in plasma region are recovered as

$$n_{pl} = \frac{\sigma_{pl} + N_d}{2}, \quad p_{pl} = \frac{\sigma_{pl} - N_d}{2}. \tag{52}$$

It can be derived easily from the continuity of electron and hole flows that $n^* > n_{pl}$ and $p^* < p_{pl}$ [see Eq. (33)]. In contrast, the relation between $\sigma^*$ and $\sigma_{pl}$ is not universal: $A < 1$ when $v^*_s \leq 0$, but $A > 1$ for $v^*_s > 0$ and $v_f > (v_f^2 - v^*_f^2)/(v^*_f)^2$. Therefore, according to Eq. (51), $\sigma_{pl} < \sigma^*$ when $v_{ns} > v_{ps}$ for any $v_f$. However, for sufficiently large $v_f$ we find that $\sigma_{pl} > \sigma^*$ when $v_{ns} < v_{ps}$. Next, $A \rightarrow 0$ for $v_f \rightarrow v_{ns}$ and hence according to Eqs. (49) and (52) $\sigma_{pl} \rightarrow N_d \sigma_{pl} \rightarrow N_d, p_{pl} \rightarrow 0$. This is consistent with the condition $v_f > v_{ns}$.

For the special cases (a), (b), and (c) when electron and hole drift velocities are equal it is convenient to use the approximation $v(E) = v(E)/(E + E_s)$ in the whole range of electric fields including plasma. After similar derivations we find
The dependence that has been discussed above in Sec. III C is clear if we take into account that, according to Eq. (50) in the symmetric case $E_{pl} \sim v_f/\sigma_{pl}$, $E_{pl}$ decreases and increases when the increase of $v_f$ with $\sigma_{pl}$ is superlinear and sublinear, respectively. Hence, “plateau” on the dependence $E_{pl}(v_f)$ corresponds to a minimum on $E_m(v_f)$.

### H. Voltage over the structure

The voltage over the structure is given by the integral

$$u = \int_0^W E(x)dx. \quad (56)$$

We approximate the actual profile $E(z)$ by a piecewise linear profile A–B–C–D shown in Fig. 10, neglecting the voltage drop over the plasma region where the electric field is low. For such profile $\sigma(z)=\sigma_0$ and $dE=b-c\sigma_0$ on part A–B, $E=E_{th}$ and $\sigma$ increases from $\sigma_0$ to $\sigma^*$ in arbitrary way on part B–C, and $\sigma(z)=\sigma^*$ and $dE=b-c\sigma^*$ on part C–D. Integration over this profile gives an upper bound for the actual voltage. On the $(\sigma, E)$ plane this profile corresponds to the rectangular $\sigma(E)$ dependence (dashed line A–B–C–D in Fig. 2). The integral over $z$ can be replaced either by the integral over electric field $E$ or over concentration $\sigma$ since, according to Eqs. (24) and (25), $dz=dE/(b-c\sigma)=d\sigma/\lambda \beta_{eff}(E_0)\sigma$. Employing integration over $E$ for branches A–B and C–D and integration over $\sigma$ for branch B–C, we approximate the integral Eq. (56) as

$$u = \int_{E_{th}}^{E_m} E \, dE \, \frac{E \, dE}{b-c\sigma_0} + \int_{0}^{\sigma^*} \frac{E_{th} d\sigma \, E_{th}}{\lambda \beta_{eff}(E_0)\sigma} + \int_{E_m}^{0} E \, dE = \int_{E_{th}}^{E_m} E \, dE + \int_{0}^{\sigma^*} \frac{E_{th} d\sigma \, E_{th}}{\lambda \beta_{eff}(E_0)\sigma} + \int_{E_m}^{0} E \, dE. \quad (57)$$

This yields...
Here, the first term corresponds to the contribution of the nonlinear part of the profile near its maximum. The ratio of the first term to the second one can be estimated as \( v_s \alpha(E_m) \tau_p \), where \( v_s \alpha(E_m) \) is the frequency of impact ionization, \( \tau_p = \ell_p / v_f \) is the time the front takes to move over its own width \( \ell_p \), and it is assumed that \( v_s = v_p \), \( \alpha_s = \alpha_p \), \( v_f \gg v_s \). [For this estimate we assume \( E_m \gg E_{\text{left}} \) and employ Eq. (43).] Typically \( v_s \alpha(E_m) \tau_p \gg 1 \) and hence the first term in Eq. (58) dominates over the second one. It means that the nonlinear part of the profile \( E(z) \) which is located near its maximum is small, and the typical shape of \( E(z) \) is close to triangular.

Taking into account that \( E_{\text{left}} = E_m - b \chi_f \), we can represent \( u \) as

\[
 u \approx E_m x_f - \frac{b x_f^2}{2} + \frac{E_m^2}{2 b \ln(\sigma^* / \sigma_0)} + \frac{E_m}{\lambda \beta_{\text{eff}}(E_m)} \ln(\sigma^* / \sigma_0). 
\]

Since the dependencies \( \sigma^*(v_f) \) and \( E(v_f) \) are already determined [see Eqs. (31) and (35)], Eq. (59) gives \( u \) as a function of front position \( x_f \) and velocity \( v_f \).

### IV. ULTRAFAST FRONTS (\( v_f \gg v_s^* \))

The front velocity \( v_f \) is often much higher than \( v_s \). In the respective limiting case \( v_f / v_s^* \gg 1 \) the effect of transport asymmetry vanishes. As it follows from Eqs. (28), (31), and (51), the concentrations \( \sigma_m \) and \( \sigma^* \) can be presented as

\[
 \sigma_m = \frac{v_f}{v_s^*} \sigma_d, \quad \sigma^* = \frac{v_f}{v_s^*} \sigma_d \ln(\sigma^* / \sigma_0). 
\]

The plasma concentration and electric field in plasma are given by

\[
 \sigma_m = \left[ 1 - \frac{(v_s^*)^2}{v_f^2} \right] \sigma^* \approx \sigma^*; \quad E_m = \frac{E_f}{\ln(\sigma^* / \sigma_0)}. 
\]

The maximum field is determined by [see Eq. (34)]

\[
 \int_0^{E_m} \left[ \sigma_m \alpha(E) + \sigma_p \alpha_p(E) \right] dE = \frac{q \sigma_d N_d}{v_f \sigma_0}. 
\]

Let us compare these predictions with the results of an elementary model suggested for a planar ionization front in diode structures in Ref. 17 on the basis of the ideas developed for fingerlike streamers in Ref. 31 and 32. In Ref. 17 it is assumed \( v_n = v_p \), \( v_f \gg v_s \), \( \alpha_p = 0 \), and \( \alpha_n(E) = \alpha_0 \Theta(E - E_{\text{th}}) \), where \( \Theta(E) \) is the step function. Under these assumptions the order of magnitude values of \( v_f \) and \( \sigma_m \) has been evaluated as

\[
 v_f = \frac{\ell_f}{\tau}, \\
 \tau = \frac{1}{v_s \alpha_0} - \ln(\sigma_d / \sigma_0), \\
 \ell_f = \frac{E_m - E_{\text{th}}}{q \sigma_d N_d / e \varepsilon_0}. 
\]
\[ \sigma_{pl} = \frac{\alpha_0 e E_0 E_m}{q} \]  \hspace{1cm} (63)

where \( \tau \) is the time it takes for the front to pass over the width of ionization zone \( \ell_f \).

For \( \alpha_p(E) = 0 \) and \( \alpha_p(E) \neq 0 \), we obtain from Eq. (62),

\[ v_f = \frac{\ell_f}{\tau}, \quad \tau = \frac{1}{v_f \alpha_0} \ln \frac{\sigma_m}{\sigma_0}. \]  \hspace{1cm} (64)

Then, it follows from Eqs. (60), (61), and (64) that

\[ \sigma_{pl} = \frac{\alpha_0 e E_0 (E_m - E_{th})}{q} - \sigma_m \ln\frac{\sigma^*}{\sigma_m} = \frac{\alpha_0 e E_0 (E_m - E_{th})}{q}. \]  \hspace{1cm} (65)

Predictions for \( v_f \) given by Eqs. (63) and (64) differ in the definition of \( \tau \). However, the relative difference \( (\tau - \bar{\tau})/\tau = \ln(\sigma^*/\sigma_0)/\ln(\sigma^*/\sigma_0) \) does not exceed 10\% (see Fig. 3). Next, according to Eq. (63) \( \sigma_{pl} \) is proportional to \( E_m \), whereas more the accurate Eq. (65) predicts proportionality to the difference between \( E_m \) and \( E_{th} \). Therefore, Eq. (63) overestimates \( \sigma_{pl} \). Still, it gives the correct order of \( \sigma_{pl} \) since in practice \( E_{th}, E_m, \) and \( |E_{in} - E_m| \) are of the same order of magnitude.

V. NONSTATIONARY PROPAGATION

A. Adiabatic condition

The relations between \( v_f, E_m, \sigma_{pl}, \) and \( E_{pl} \) obtained for \( J = \text{constant} \) still hold when \( J \) varies in time providing that this variation is slow in comparison with inner relaxation times of the traveling front. These times are the Maxwellian relaxation time in plasma behind the front \( \tau_M \) and the time \( \tau_p = \ell_f/v_f \) the front takes to move over the width of the screening region \( \ell_p \). Indeed, any change of the electric field (and hence the current density) in the \( n \) base originates from changes of electric charges in the highly doped \( p^+ \) and \( n^+ \) layers that serve as effective electrodes (see Fig. 1). Further transfer of electric charge into the \( n \) base occurs through the plasma layer and is controlled by \( \tau_M \). Redistribution of charges in the traveling screening region at the plasma edge takes time \( \tau_p \). Thus, the times \( \tau_M \) and \( \tau_p \) characterize how fast the front relaxes to the steady profile that corresponds to the instant value of the current density. Employing Eq. (43), assuming for simplicity \( v_f = u_m = v_p, \mu = \mu_n = \mu_p, \) and taking into account \( v_f = \mu E_f, \) we obtain

\[ \tau_p = \frac{\ell_p}{v_f} = \tau_M E_m \sigma_{pl}, \quad \tau_M = \frac{E_{pl}}{q \mu \sigma_{pl}}. \]  \hspace{1cm} (66)

We see that \( \tau_p \) is much larger than \( \tau_M \) and hence it is the time \( \tau_p \) that eventually controls the relaxation of the front profile.

Consequently, the adiabatic condition for the variation of current \( J \) can be presented as

\[ \frac{d(\ln J)}{dt} \ll 1. \]  \hspace{1cm} (67)

Below, we show that this condition is typically met for the realistic operation mode of high-voltage diodes used as switches in pulse power applications.

B. Coupling to the external circuit

In practice the device is connected to the voltage source \( U(t) \) via a load resistance \( R \). The current density \( J \) and the voltage over the structure \( u \) are related via Kirchhoff’s equation,

\[ u(t) + RJ(t) = U(t). \]  \hspace{1cm} (68)

In high-voltage diodes used in pulse power applications the front passage switches the structure from the nonconducting state to the conducting state. At the moment \( t = t_0 \), when the front starts to travel, \( u = U(t_0) \) and \( J = 0 \). The switching time is determined as \( \Delta t = W/\langle v_f \rangle \), where \( W \) is the \( n \) base width and \( \langle v_f \rangle \) is the mean value of front velocity (generally, \( v_f \) increases during the front passage). The device resistivity after switching is negligible in comparison with the load resistance \( R \). Hence \( u(t_0 + \Delta t) = 0 \) and \( J(t_0 + \Delta t) = U(t_0 + \Delta t) / (RS) \approx U(t_0 + \Delta t) / (RS) \), where we take into account that variation of \( U \) within the time period \( \Delta t \) is small. Then, we estimate the relative variation of the current density as

\[ \frac{d(\ln J)}{dt} \approx \frac{J(t_0 + \Delta t) - J(t_0)}{\Delta t / \langle v_f \rangle} \approx \frac{1}{\Delta t / \langle v_f \rangle}. \]

Substituting this estimate into Eq. (67), we present the adiabatic condition as

\[ \frac{\langle v_f \rangle}{v_f} \frac{\ell_p}{W} \approx \frac{\ell_p}{W} \ll 1. \]  \hspace{1cm} (69)

Equation (69) states that the inner dynamics of the traveling front and the outer dynamics that is controlled by the external circuit can be separated if the effective front width \( \ell_p \) is much smaller than the size of the system \( W \). Using Eq. (43), we present Eq. (69) as

\[ \frac{E_m}{bW \ln(\sigma^*/\sigma_0) - 1} \ll 1. \]  \hspace{1cm} (70)

According to Eq. (42) and Fig. 7, the second term in Eq. (70) has a numerical value in the range 0.05–0.1. Therefore, it is necessary that \( E_m / (bW) \sim 1 \). The adiabatic conditions Eqs. (69) and (70) are met or nearly met for high-voltage sharpening diodes where \( W \sim 100–300 \mu m \) and \( \ell_p \sim 10–20 \mu m \), but are not likely to be met for much smaller TRAPPATT diodes.

In conclusion, the relations between \( v_f, E_m, \) and \( \sigma_{pl} \) obtained for the self-similar propagation mode can be used in general case to relate the instant values of these parameters for sufficiently large structures and fast fronts. In this case the voltage \( u(v_f, \theta_f) \) given by Eq. (59) can be substituted into the Kirchhoff equation, Eq. (68). Then, equation \( \text{d}x_f/\text{d}t = -v_f \) (recall that \( v_f > 0 \) for the front traveling in the negative \( x \) direction) together with Eq. (68) represents a set
of ordinary differential equations that describes the front propagation with the external circuit taken into account.

VI. SUMMARY

Basic parameters of plane impact ionization fronts in reversely biased $p^+-n-n^+$ structure (Fig. 1) are determined by current density $J$ and concentration of initial carriers $\sigma_0$ (regime parameters), doping of the $n$ base $N_d$ (structure parameter), and such material parameters as saturated drift velocities $u_n$ and $u_p$, low-field mobilities $\mu_n$ and $\mu_p$, and electron and hole impact ionization coefficients $\sigma_n(E)$ and $\sigma_p(E)$. The front velocity is given by $v_f = J/qN_d$ [Eq. (12)]. The concentration of generated plasma $\sigma_{pl}$ and electric field in plasma $E_{pl}$ determined by Eqs. (28), (31), and (49) does not depend on impact ionization coefficients $\sigma_{n,p}(E)$. Concentration of $\sigma_{pl}$ weakly decreases with initial carrier concentration $\sigma_0$ [Fig. 8(a)]. For moderate front velocities $v_f \leq 5(u_n + u_p)$ the concentration $\sigma_{pl}$ and field $E_{pl}$ are sensitive to the ratio $u_n/u_p$, whereas the asymmetry in low-field transport $\mu_n/\mu_p \neq 1$ has very little effect [Figs. 8(b) and 9(b)]. For higher front velocities $\sigma_{pl}$ and $E_{pl}$ do not depend on $u_n/u_p$ and $\mu_n/\mu_p$ [Eq. (61)]: $\sigma$ increases with $v_f$ quasi-linearly, whereas $E_{pl}$ weakly decreases.

General dependence of maximum electric field $E_m$ on $v_f$ is given by Eq. (35). Due to strong nonlinearity of impact ionization coefficients $\sigma_{n,p}(E)$, often only one type of carrier contributes to ionization. In this case the dependence $E_m(v_f)$ can be determined in a simple form for the Townsend's approximation $\sigma(E) = \sigma_0 \exp(-E_0/E)$ and symmetric transport $u_n = u_p$ [see Eq. (36) and Fig. 4]. We reveal the existence of the effective threshold of impact ionization $E_{th} = 0.2E_0$ (Figs. 5 and 6) and the squareroot character of the $E_m(v_f)$ dependence [Eq. (40)]. Equation (40) implies that $v_f \sim \ell_f^2$, where $\ell_f$ is the effective width of ionization zone. The square-root dependence fails for slow fronts when $\sigma_p \ll \sigma_n$, $E_n$ increases with $E_0$ and $N_d$ (Fig. 6) and decreases with $\sigma_0$ and $\sigma_n$ (Figs. 4–6). The width $\ell_p$ of the screening region where electric field falls from $E_m$ to $E_{pl}$ weakly depends on $\ell_f$ and $\sigma_0$ [Eq. (42)]. The slope of the electric field in the screening region is about 10–20 times larger than the slope $qN_d/e\epsilon_0$ in the depleted $n$ base to which the front propagates (Fig. 7).

The voltage over the structure $u$ is determined by the front velocity $v_f$ and the front position $x_f$ [Eq. (58)]. The profile of electric field $E(z)$ is essentially triangular since the nonlinear part near its maximum $E = E_0$ is small.

In the case when the current density $J$ varies in time, the front velocity $v_f$ and the front profile $E(z)$ is nonstationary. The largest inner relaxation time $\tau_{pl} = \ell_f^3/v_f$ is the time it takes for the front to travel over the width of the screening region $\ell_p$ [Eq. (66)]. The relations between basic front parameters $E$, $\ell_p$, $\sigma_{pl}$, and $E_{pl}$ obtained for $J$-constant remain valid if temporal variation of $J$ is slow with respect to $\tau_{pl}$ [Eq. (67)]. For the actual case of the device connected in series with an external load, this adiabatic condition [Eq. (67)] can be presented as $\ell_p / W \ll 1$ [Eq. (69)]: inner and outer dynamics can be separated if the ionization front is thin with respect to the $n$ base width $W$. This condition is met or nearly met for high-voltage sharpening diodes.

For very strong electric fields $E \geq E_0$, the direct band-to-band tunneling (Zener breakdown) must be taken into account. Numerical simulations show that in the presence of this ionization mechanism the character of front propagation substantially changes. The respective fronts have been called tunneling-assisted impact ionization fronts. Recently, the dynamic avalanche breakdown of high-voltage diodes with stationary breakdown voltage $U_b \approx 1.5$ kV at extremely high voltage about 10 kV, which corresponds to electric fields above the threshold of Zener breakdown, has been observed experimentally. The analytical theory of tunneling-assisted impact ionization fronts will be reported separately.

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26Generally, emission from deep-level centers can create nontrivial and non-

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stationary profile of initial carriers in the n base. However, our theory reveals weak logarithmic dependence of all major front parameters on $n_0$ and $p_0$. This justifies our assumption that $n_0$ and $p_0$ maintain constant values in the depleted region.


